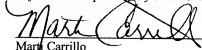


PATENT

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

I hereby certify that this correspondence is being electronically filed with the United States Patent and Trademark Office on April 17, 2008 at or before 11:59 p.m. Pacific Time under the Rules of 37 CFR § 1.8.



Marc Carrillo

Applicant : Nam Hun Kim
Application No. : 10/593,857
Filed : September 22, 2006
Title : PLASMA CHAMBER HAVING PLASMA SOURCE COIL AND
METHOD FOR ETCHING THE WAFER USING THE SAME
Grp./Div. : 1792
Examiner : Duy Vu Nguyen Deo
Docket No. : 58409/N305

Confirmation No. 5813

RESPONSE TO RESTRICTION REQUIREMENT / ELECTION

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Post Office Box 7068
Pasadena, CA 91109-7068
April 17, 2008

Commissioner:

In response to the Office action dated March 18, 2008, applicant hereby elects Group I, claims 1-6.

Applicants reserve the right to pursue the non-elected (withdrawn) claims in a Divisional application.

Respectfully submitted,

CHRISTIE, PARKER & HALE, LLP



By _____
D. Bruce Prout
Reg. No. 20,958
626/795-9900